

Activities in Task 14.3.1

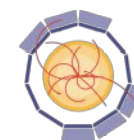
Test infrastructure for innovative calorimeters with semiconductor readout

Vincent Boudry

École polytechnique, Palaiseau



AIDA-2020 2nd Annual Meeting
04-07/04/2017, Paris



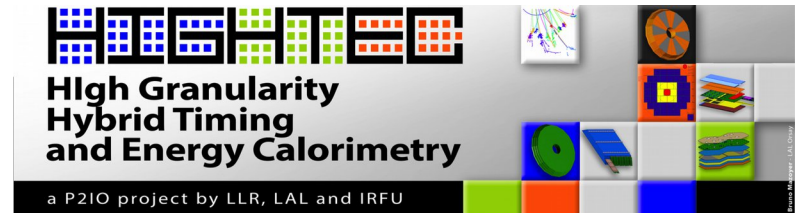
AIDA 2020

TNA support + WP14

Recent news on SiW-ECAL

Funding from Paris-Saclay P2IO “physics of 2 Infinities and Origins” Grant → LLR, LAL & IRFU (CEA)

- **HGCFC: High-Granularity Calorimeters for future Colliders started (oct. 2016).**
dubbed “**HiGHTEC**” in between
 - SiW-ECAL for LC’s
 - CMS-HGCAL ⊃ timing studies
 - ATLAS-HGTD design & studies
- **Complementary of AIDA-2020:**
 - Completion of SiW-ECAL prototype; Study of long slab; Mechanical studies
 - DAQ for ILD
- **2 post-docs recruited for 2 years:**
 - **Adrian Irlles (WP5)** (since 7/11/16) @ LAL on SiW-ECAL : DAQ & tests
 - **Artur Lobanov** (≥1/12) @ LLR on SiW-ECAL (25%) & CMS-HGCAL(75%): SK2(a) test & analysis



Coord. Y. Sirois

Plans for 2017 in a nutshell...

Test completely the 10 SLAB's produced in 2016

- **June 2016 tests: mitigated results**
 - SiW-ECAL suffered from noise (of still unknown origin)
 - ⇒ « SLAB's not tested in beam »
 - DAQ development (SiW-ECAL+ SDHCAL) ✓
 - Shown to work; To be completed with working prototype
- **Standalone tests in June @ DESY**
 - Improvement of DQM & DAQ (Adrian @ LAL)
 - Improvement of Power Supplies (LAL & LLR)
 - Some behaviour linked to number of SLABs in operation
 - Review of the procedure to optimise the noise & retriggering handling in the chips
 - Thorough check of rates vs conditions:
 - » slower clock (less edges)

~~Combined tests with SDHCAL~~ → Fall

- **after June validation**
 - test in IPNL of both set-ups
- **news mechanical structure**
 - Flexible number of layers, for $24X_0$ W

End March: Decision
not to go in 2017:
manpower issues

Production of additional layers with SK2A & 525 μ m wafers

- **Tests of SK2A (many improved features): on-going**
- **Test of wafers HPK wafers : received. To be tested @ LPNHE**
- **new PCB FEV12 ordered (to be received this week)**
- **Assembly bench adaptation @ LLR ⊗ LPNHE ⊗ LAL**
 - thicker wafers for shorts slabs
 - **Long SLAB preparation**
 - Test of gluing with thin PCB's

Preparation of June 2017 BT @ DESY

June 12–24th in DESY, TB24/1 (PCMag line)

- Test 10 SLABs, with SK2 (same as June 2016)
- Possibility to have B filed test of electronics (secondary goal)
 - 120-130kg. Usable $\varnothing \sim 75\text{cm}$

Ralf Diener, Norbert Meyners, Marcel Staritzki - DESY Test Beam Coordinators

Week	TB21	TB22	TB24/1	TB24
2-Jan-17	1			
9-Jan-17	2			
16-Jan-17	3			
23-Jan-17	4			
30-Jan-17	5			
6-Feb-17	6			
13-Feb-17	7			
20-Feb-17	8			
27-Feb-17	9			
6-Mar-17	10			
13-Mar-17	11			
20-Mar-17	12			
27-Mar-17	13			
3-Apr-17	14			
10-Apr-17	15			
17-Apr-17	16			
24-Apr-17	17			
1-May-17	18			
8-May-17	19			
15-May-17	20			
22-May-17	21			
29-May-17	22			
5-Jun-17	23			
12-Jun-17	24			
19-Jun-17	25			
26-Jun-17	26			
3-Jul-17	27			
10-Jul-17	28			
17-Jul-17	29			
24-Jul-17	30			
31-Jul-17	31			

Shutdown

BELLE-II

Summer Shutdown

Announced

Test set-up:

- Remounted at LAL for implem of DQ (Adrian Irlès)
- DAQ updates (Pyrame v3, \supset improved online rec.)
- Power Distribution to be rebuild.

Testbench(es) 2017



■ DAQ + Power Supplies rack from LLR

- Plug & Play

■ Prototype equipped with 5 FEV10 modules with 16 chips (skiroc 2), 64 chn each = 5120 chn.

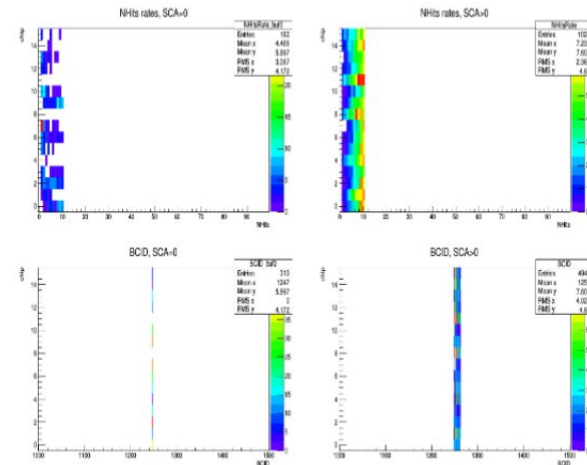
- 5 more at LLR to be integrated in the prototype for beam test.

■ Data taken at LAL with the prototype.

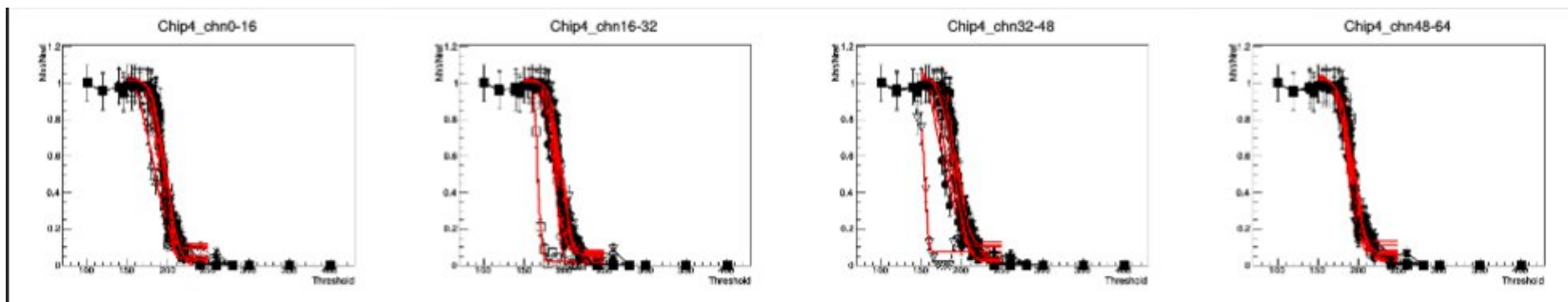
- Noise run, with low fast shaper threshold value (DAC = 190)
- FEV10, SK2.
- HV = on (110V)

■ Plots for one ASIC

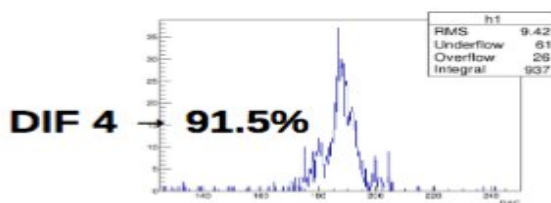
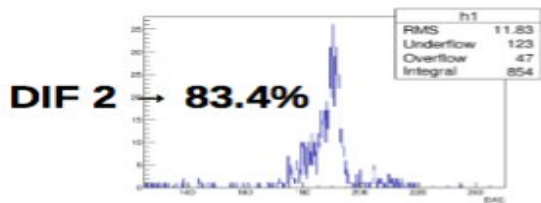
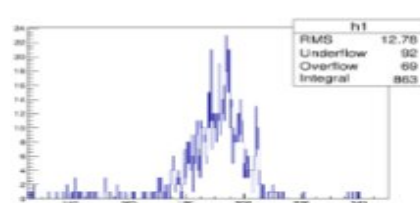
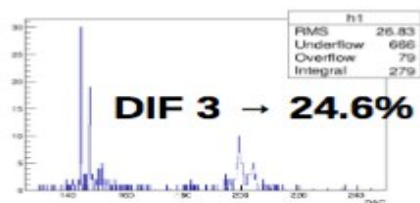
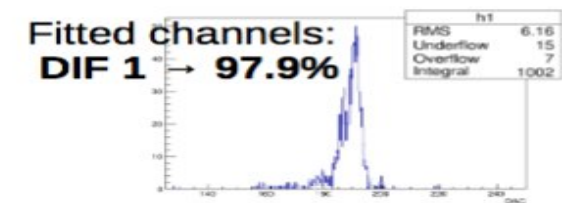
- Nhits (SCA=0 and SCA>0)
- BCID (SCA=0 and SCA>0). As the threshold is quite low, the BCIDs are ~ val_evt BCID.



Threshold scans...



■ Summary plots of optimal threshold fit for all DIFs

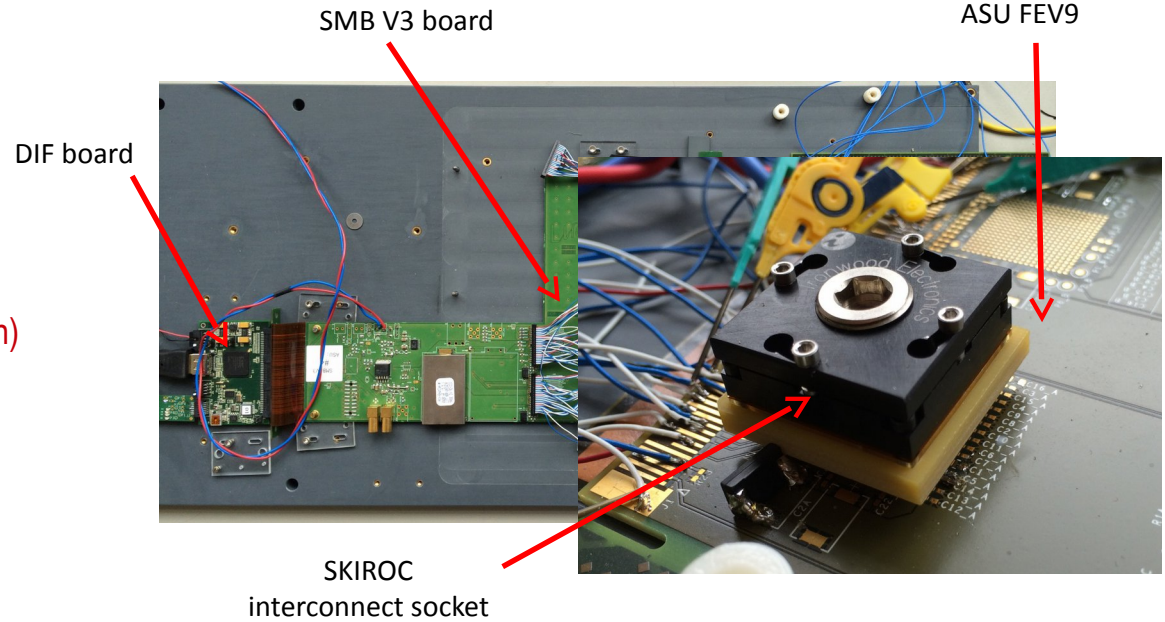


■ Not optimized analysis or results checked carefully but ... **promising.**

Test of SK2 and SK2a (LLR)

Test bench at LLR:

- FEV9 with single BGA socket
 - ASIC in power pulsing (PP)
 - CCC, LDA, DIF, SMB v3
 - FastCLK: 50 MHz, Slow CLK: 2.5MHz
 - DAQ software: Pyrame/Calicoes v2-3 (development branch)
 - Possibility of in phase signal injection
- ⊕
- Quick exchange of ASICs
 - External command lines available on FEV connectors
 - Single chip allows high spill frequencies (up to 60 Hz)
- ⊖
- Socket less reliable than soldering
 - Lower quality SMB-FEV connections ⇒ More exposed to noise



⇒ Thorough check of running cond. with single chips
⇒ Procedure for SLABs

A. Lobanov, S. Chaitanya, V. Boudry, J. Nanni

ASIC testing: set-ups

From : Izumi Sekiya, LCWS2016

Tests of SK2A (outside of Ω mega):

- **Dedicated test board (all protections on)**
 - Kyushu #LabView (copy of Ω mega)
 - Ω mega \leftrightarrow LLR (CMS & CALICE)
 - Adaptation to PYRAME (Yannick Geerebaert)
 - » S2A \rightarrow SK2CMS

⊕

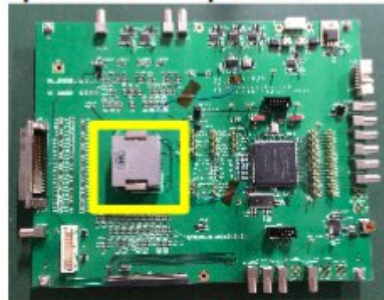
- **ASIC soldered on board**
- **Decoupling capacitances on all critical power line**
- **External and internal signals available**

⊖

- **No power pulsing possible**
- **ASIC not replaceable**

Testboard1

- Being equipped with a BGA socket
- ASIC chip can be replaced easily

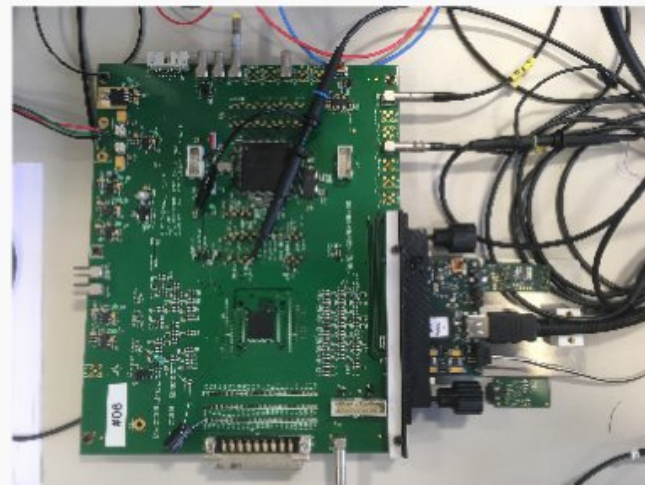


Testboard2

- SKIROC2A is directly mounted on the board



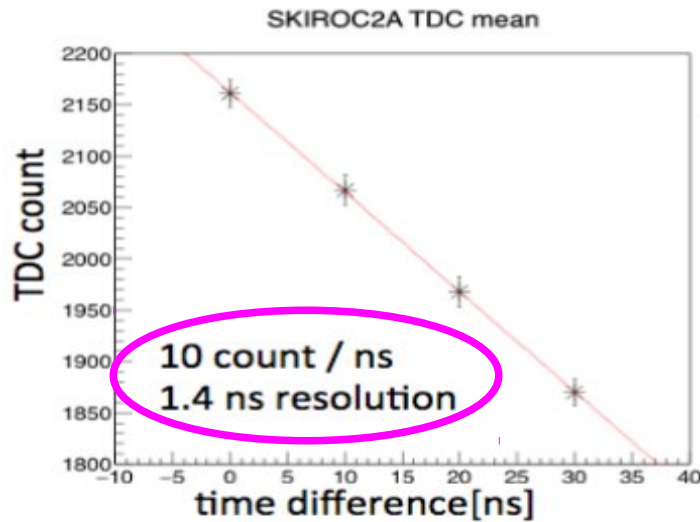
New Ω test board for SKIROC2A produced with DIF connector



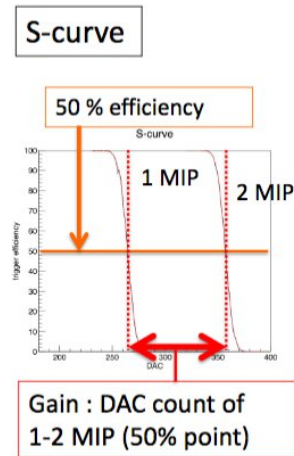
SK2A first results

Thorough checks on 1 mip injected signal (Izumi Sekiya for Kyushu group)

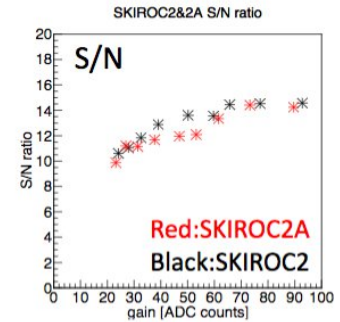
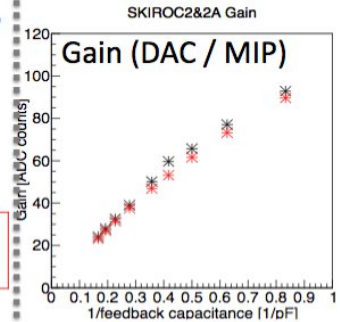
- All seems OK
- No difference in Analog part
- Trigger:
 - large channel-by-channel adjustment ✓
- TDC
 - Working!



Fast shaper & triggering @SKIROC2,2A



- Test pulse in ch10
- Preamp of all ch active
- Trigger of all ch active
- Dependence on gain by feedback capacitance
- Socket version of testboard is used

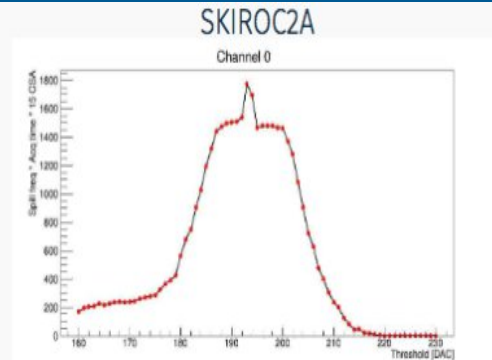
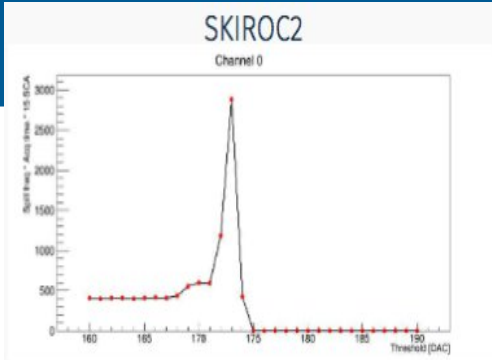
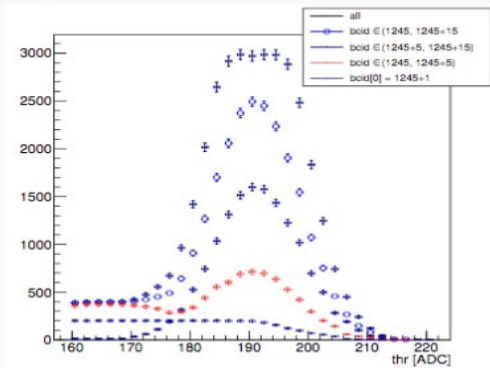
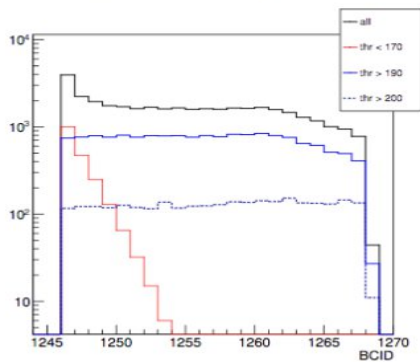


S/N=13~14, no difference seen between SKIROC2/A

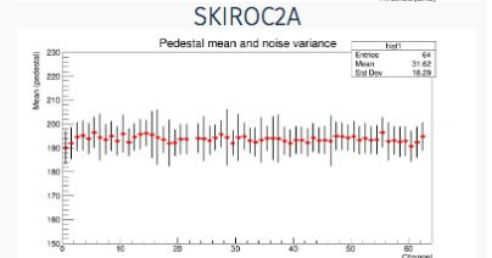
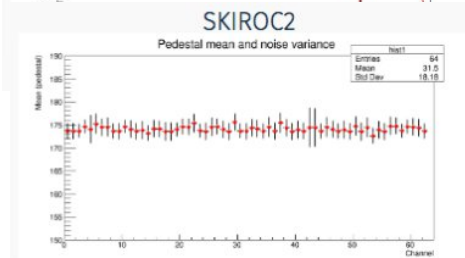
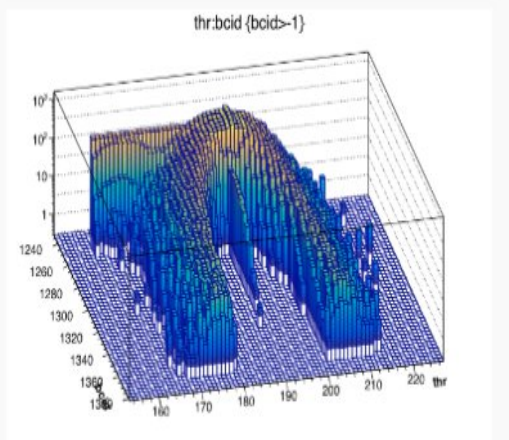
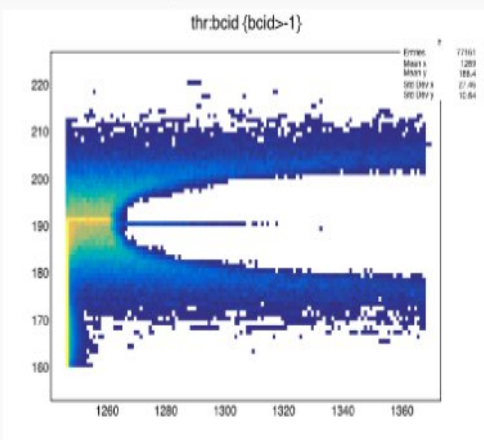
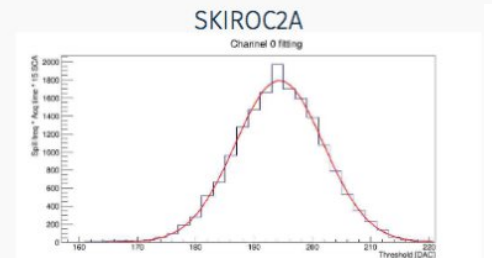
Noise on Trigger Channel

S-curves (single chan scan)

- Acquisition length: $10\mu\text{s}$ (spill length: 1.410ms)
- Sometimes "val_event" seems to trigger first few SCAs



- SK2 has narrow peak (as expected), but SK2A has a wide distribution



Mean : 173.8 - 175; Variance : 0.8 - 1.3

Mean : 194 ± 1; Variance : 6 ± 0.4

- Low spread between channels in SK2 and SK2A

Planning 2017: Prototype

with 10 first SLAB's

- noise handling
 - Scans.
 - Time dependance ?
 - PS dependance ?
- Cosmic data taking
 - Δ hasher running conditions... (longer integration time)

Beam test in 12-24 June @ DESY

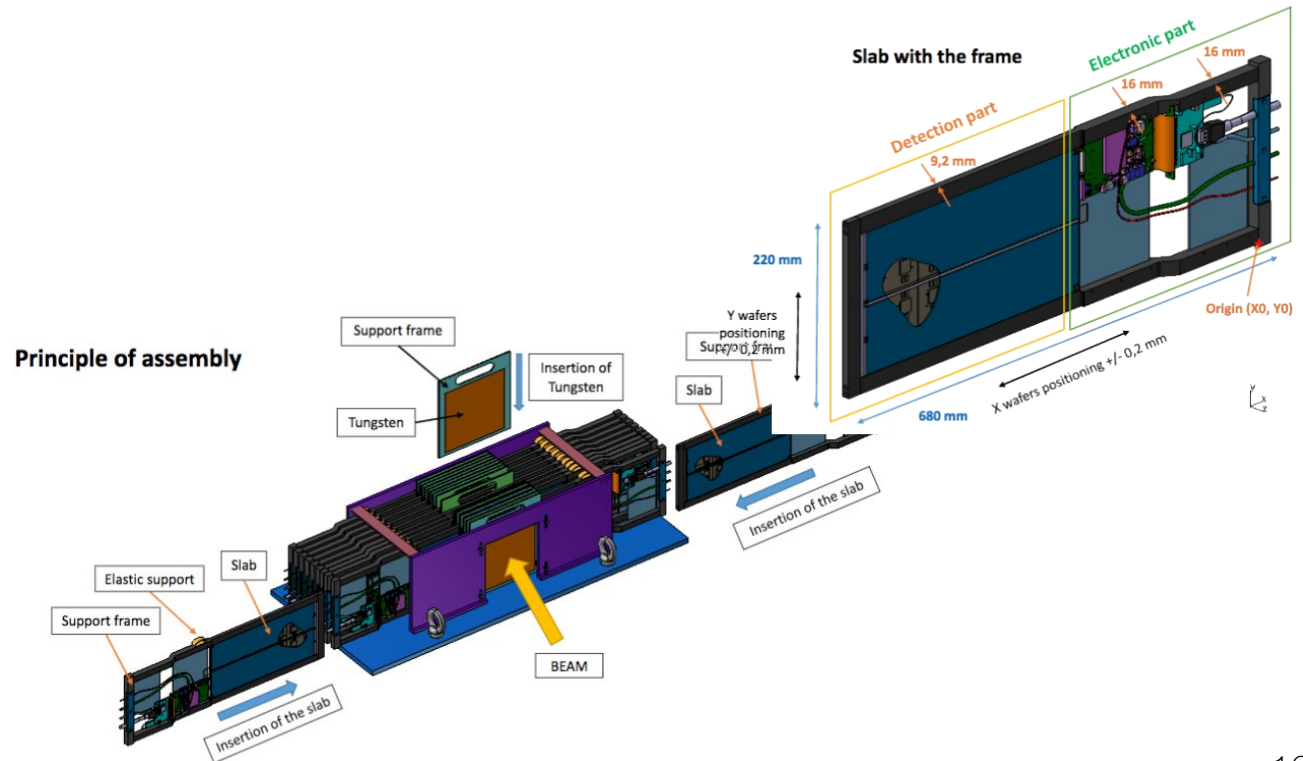
- Readiness review mi-April

Analysis + of nov 15 data.

- \Rightarrow Start of assembly for second batch ...

\Rightarrow Test of 20 SLABs early in 2018

- with new structure [Guillaume Fayolle]



Plans for 2017 in a nutshell...

Test completely the 10 SLAB's produced in 2016

- **June 2016 tests: mitigated results**
 - SiW-ECAL suffered from noise (of still unknown origin)
 - ⇒ « SLAB's not tested in beam »
 - DAQ development (SiW-ECAL+ SDHCAL) ✓
 - Shown to work; To be completed with working prototype
- **Standalone tests in June @ DESY**
 - Improvement of DQM & DAQ (Adrian @ LAL)
 - Improvement of Power Supplies (LAL & LLR)
 - Some behaviour linked to number of SLABs in operation
 - Review of the procedure to optimise the noise & retriggering handling in the chips
 - Thorough check of rates vs conditions:
 - » slower clock (less edges)
 - » absolute noise rate determination

~~Combined tests with SDHCAL~~ → Fall

- **after June validation**
 - test in IPNL of both set-ups
- **news mechanical structure**
 - Flexible number of layers, for $24X_0$ W

End March: Decision
not to go in 2017:
manpower issues

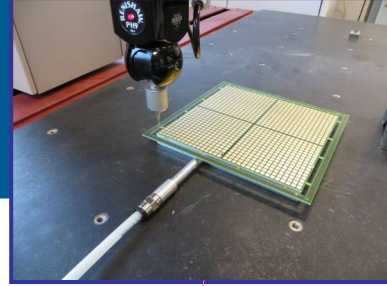
Production of additional layers with SK2A & 525 μ m wafers

- Tests of SK2A (many improved features): **on-going**
- Test of wafers HPK wafers : **received. To be tested @ LPNHE**
- **new PCB FEV12 ordered (to be received this week)**
- **Assembly bench adaptation @ LLR ⊗ LPNHE ⊗ LAL**
 - thicker wafers for shorts slabs
 - **Long SLAB preparation**
 - Test of gluing with thin PCB's

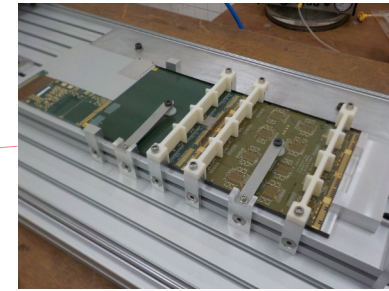
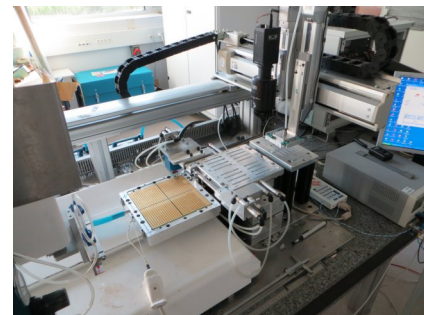
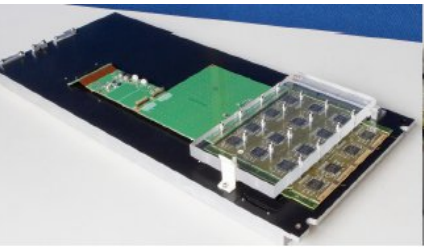
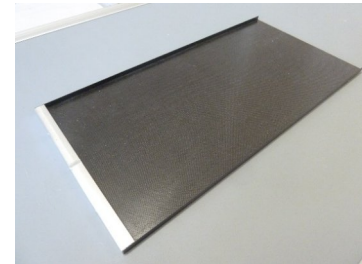
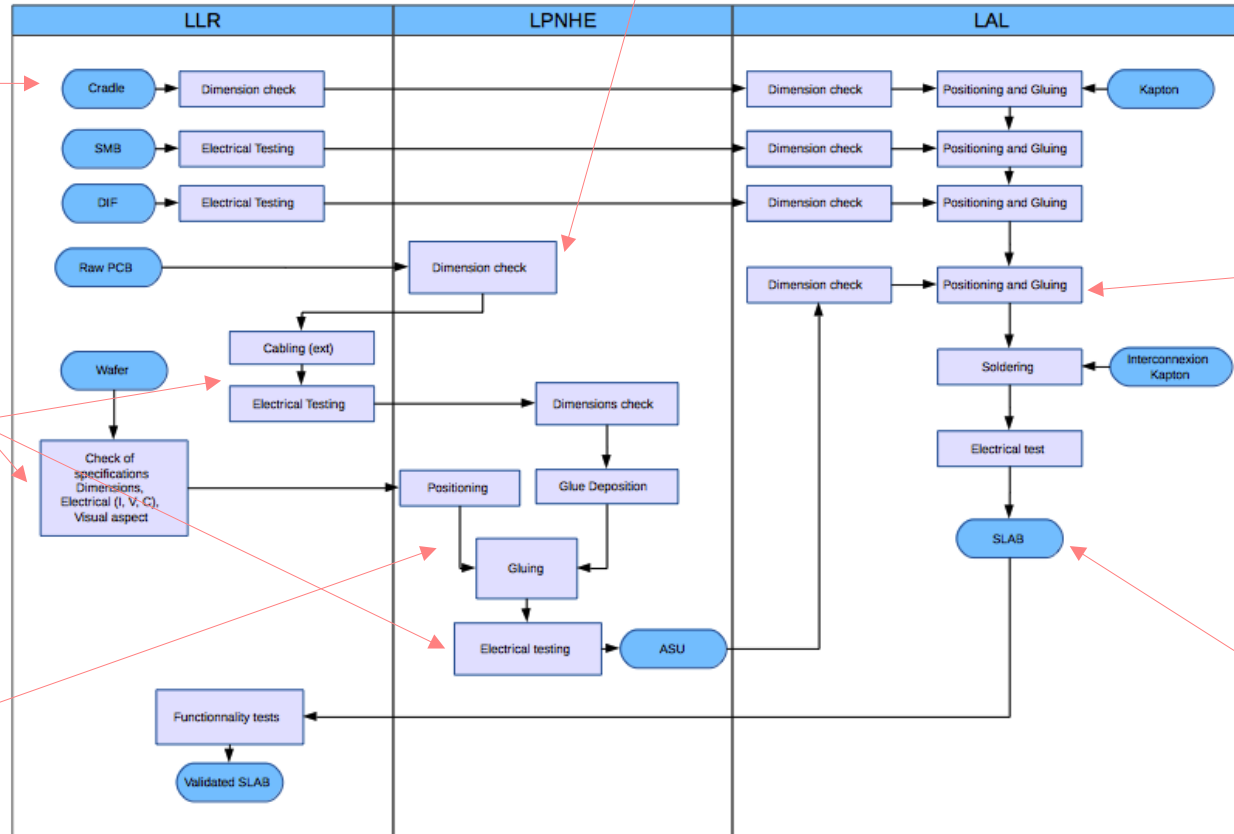
Full assembly chain

resp: R. Cornat

J. Nanni, M. Louzir, M. Frotin,
J. Bonis, P. Cornebise, J. David,
D. Lacour, S Pavy, P. Ghislain

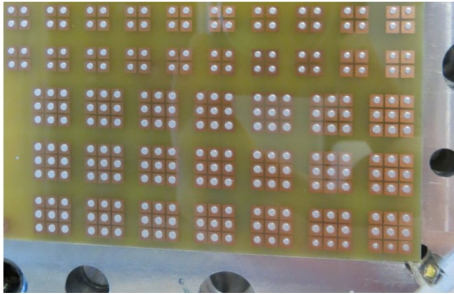


'Simplified view'

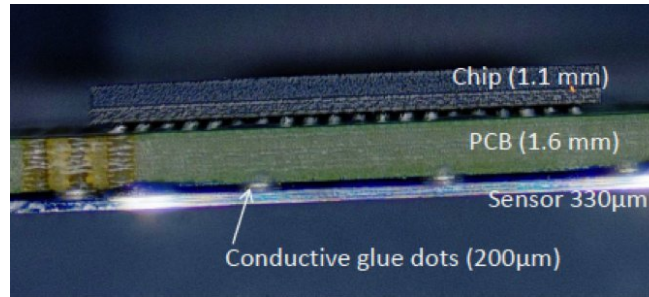


Test beam prototype and assembly process

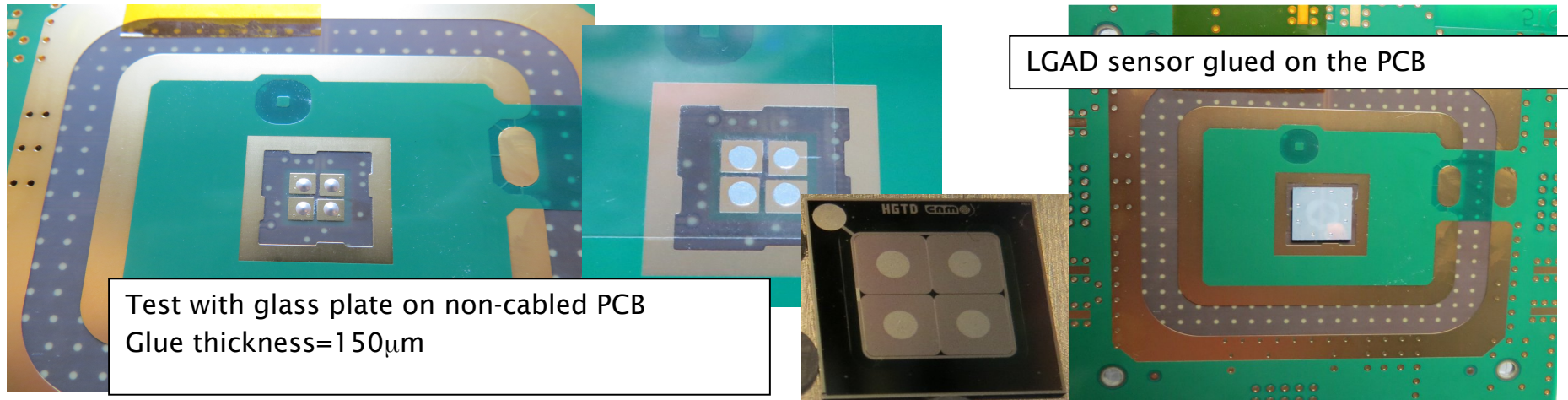
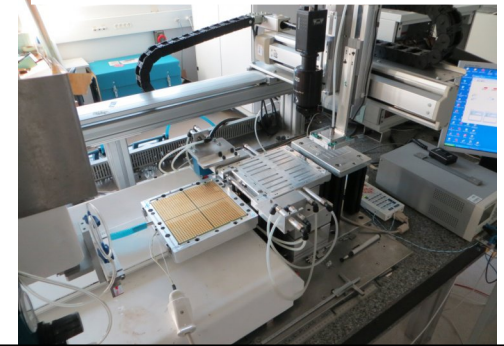
ATLAS HGTD prototype



Active Sensor Unit after gluing

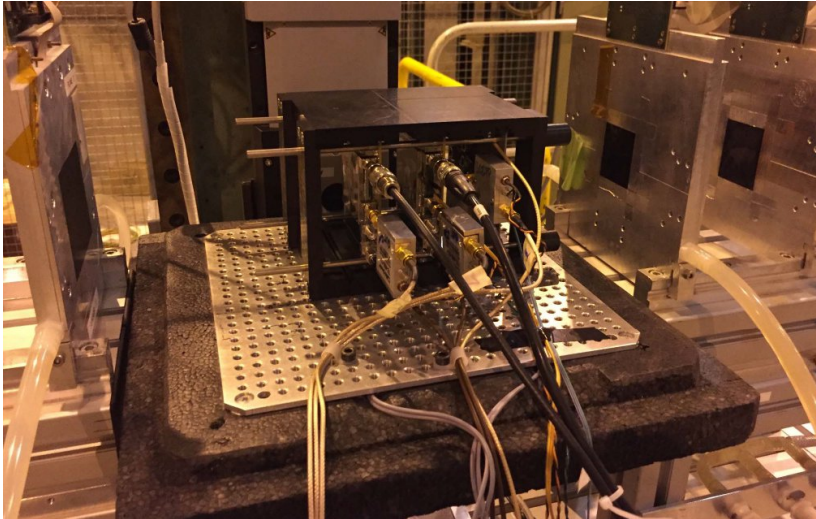


Gluing and positioning robots

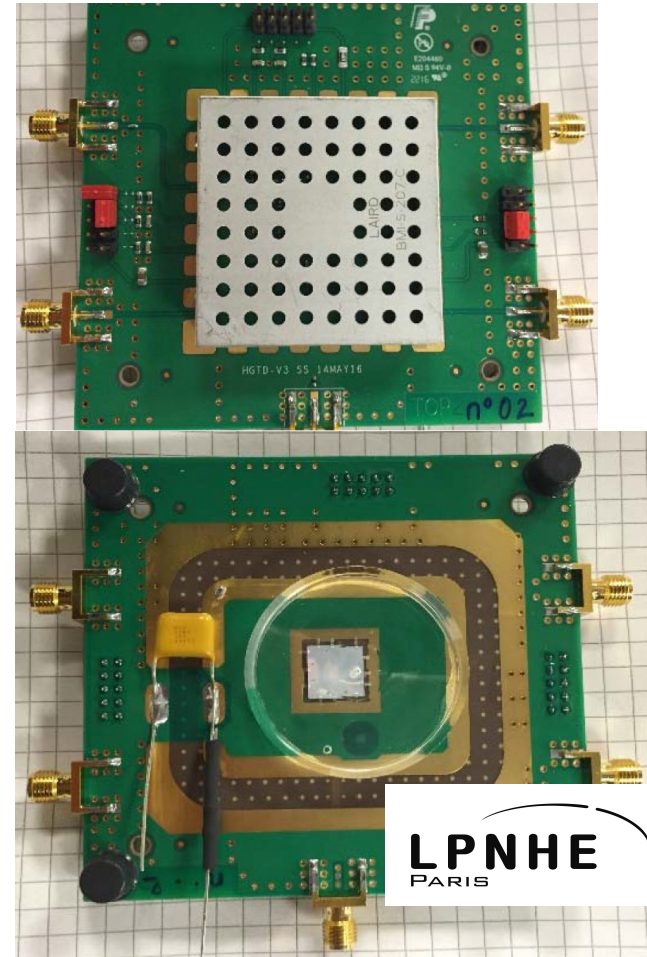


Test beam

August and November 2016 – 120 GeV pions



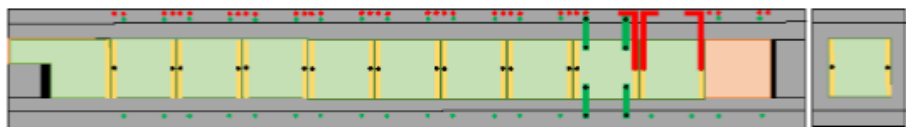
- 2 sensors IN2P3 3x3 mm²:
 - PIN diode
 - LGAD



Test bench for Long Slab Assembly

Mechanical [Julien, Alice]

- Precision needed
 - Cumulative errors \Rightarrow need for positioning



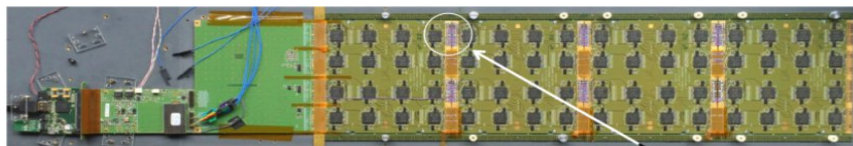
POSITIONNEMENT



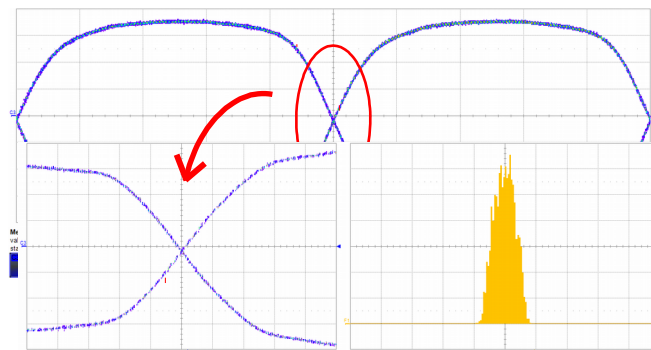
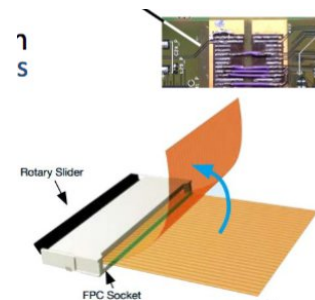
Les ASU seront posés en position sur le banc et l'alignement sera affiné mécaniquement avec l'outil rouge avant fixation et interconnexion ou collage.

- 3 methods proposed
 - with risk evaluation... in discussion.
- Assembly bench upgrade beginning of summer

Electronics [Jérôme]



- 4 ASU set-up \uparrow
- New one \Rightarrow 10-12 ASU with
 - Soldering OR Connectors
 - Some baby wafers
 - Way to emulate missing ones



Wafers (Rémi, Taikan)

“Edgeless wafers” integrated in 2 of the 10 SLABs

- needs BT data (with muon beam → edge scan)

Baby sensors

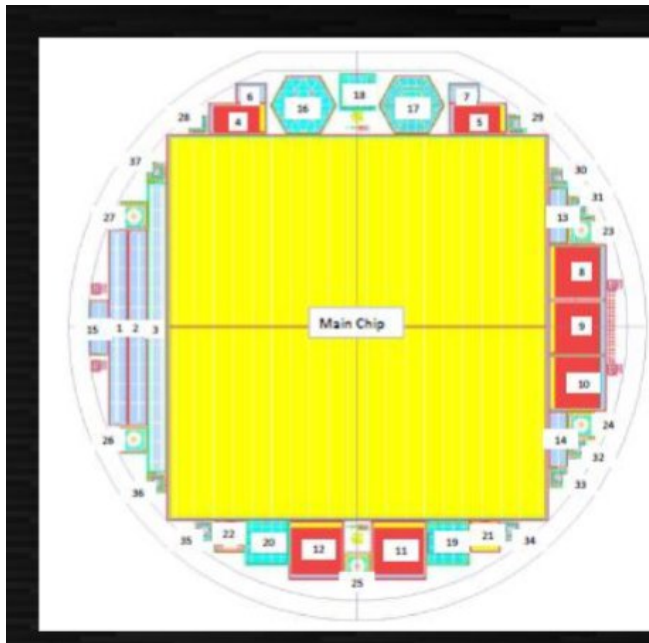
- HPK change or resistivity in 2013 (without notice)
- Parasitic production

Position Sensitive Detector

- Laser scan
 - reconstruction.

Production of SLAB in Japan (if budget)

- FEV altern.
 - existing version FPC (Kapton) ; Hexagonal 8”



320 μm thickness
lower resistivity

16,17: Hexagon
(hexagonal cells,
triangular cells)
19,20: 4x4 (small pix)
(0 GR, 2 GR, 2.5 mm)
21,22: PSD (7 mm)
(meshed, non-meshed)

Each > 40 sensors

News from HGICAL; preparation of BT in May

Some choices made during the last 2 months

- **not to** use a carbon fibre structure for HGICAL
 - more flexibility in technical choices
- **Lead/Cu** instead of **W** (for cost reasons) as absorber

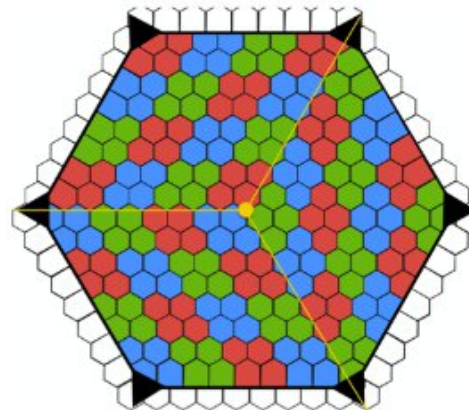
Pending: internal geometry (30° vs 60° elements)

Technical Review of Square vs Hexagonal wafer

- **started 9th of Nov. 2016, ~finished**
 - almost definitive choice made to stick to hexagonal geometry
 - review with Wafer producers of 2 options
 - » with side wafers for square
 - yield, number of channels (power consumption \propto), coverage, geometry & trigger issues, ...

ASIC's

- **SKIROC2CMS** gives acceptable results
 - ⇒ will be used for future Beam-Tests
- **SK2A** available for **SiW-ECAL**
 - Comparative tests @ LLR on-going



Deliverables & Milestones

Milestone number	Milestone	Related WPs	Est. date	Means of verification	Exp'd Del. date	
MS14	Assembly and QA chain demonstration for highly granular silicon calorimeters	14.3.1	M12	2-3 operational layers produced	30/04/16	23/06/16
MS15	Design specifications of test stations for irradiated silicon sensors and LHC oriented front-end electronics	14.3.1	M12	Report to StCom	30/04/16	24/06/16

Deliverable (number)	Deliverable name <i>(short description of deliverable)</i>	WP	Lead Participant	Type	Del. Month	Delivery Date
D14.3	Advanced Assembly chain for Si calorimeters <i>(prototypes assembly and technical documentation of process)</i>	14.3.1	CNRS	DEM	M36	30/04/18
D14.5	Common running of calorimeter prototypes <i>(technologies embedding Central DAQ standards from WP5 and performance results)</i>	14.4.1	DESY	DEM	M36	30/04/18

Networking

1) Infrastructure: To what extent is your work an infrastructure or part of an infrastructure that can be used in the European (and beyond) Research Area?

– Assembly benches techniques :

- DAQ SW (Pyrame)
- ASIC test → Omega chips,
- Spring array & Gluing benches for PCB with pad readout,
- pick and place for sensitive devices

2) Network: Does your work belong to a bigger network on similar research topics (this is similar but not exactly the same as 1))?

– P2IO: local to Paris region

3) Synergies: Do you create synergies beyond your actual field of working ?

– Counter-question: What is «the field of working» ? Silicon Sensors, Calorimetry, Detectors, HEP, Physics, Science, ... ?

4) Industrial partners: Are you in contact or will you in the near future establish sustained contacts with industrial partners (of any size)?

– Hamamatsu (Wafers), Eolane (Assembly of Electronics components)

Extras

Overview ILD & RnD

From Japan & IN2P3

- Cost reduction : → redesign of ILD



- Support in France

- IN2P3 ⇒ Prototype & Beam Test



- AIDA-2020: assembly benches & BT



- HIGHTEC from P2IO
[LLR, LAL, Saclay] ⊗ [CMS,CALICE,ATLAS]



- High Granularity Si CALOs
- R&D: Long SLABs, COB, DAQ
- PostDocs [Artur, Adrian]



Effort in design of ILD well restarted

... and documented!

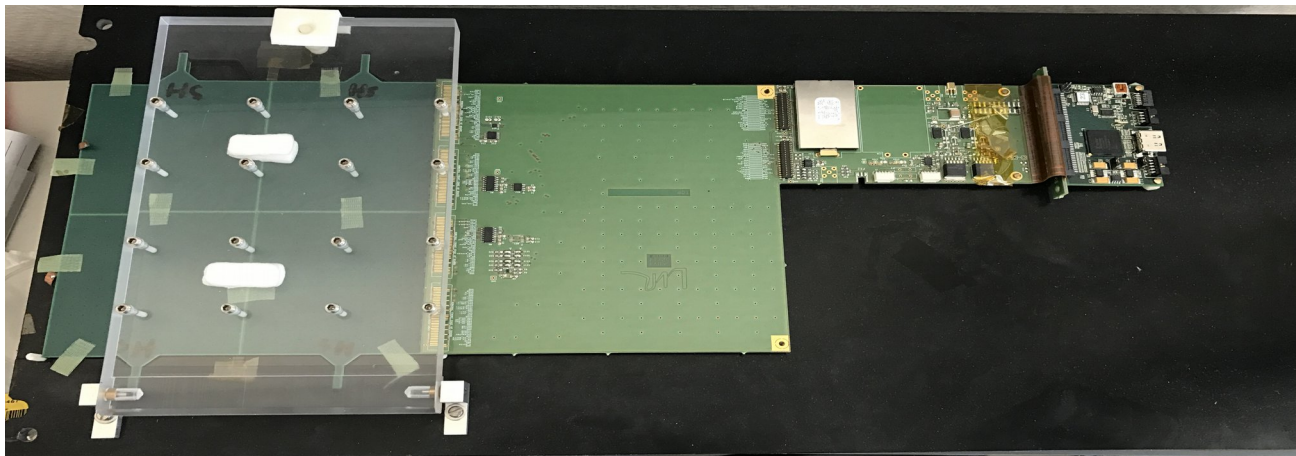
⇒ criteria for prototypes

Main priorities

- Test of prototype [June 2017, 2018]
 - And analysis
 - No more BT in sept 2017
 - Check critical Studies and R&D for ILD
 - e.g. Long SLAB
 - DAQ, geometry
- ↔ with contracts planning

Studies ASU with wafers

3rd bench



Goals:

- Measure the leakage current,
- Compare level of noise, Scurves ...
- Linearity of analog channel
- ...

